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Special Issue Reprint

CMOS-MEMS Fabrication Technologies and Devices

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This Reprint collects 10 outstanding peer-reviewed articles, focusing on CMOS-MEMS fabrication technologies and devices. The content of these articles is within the scope of a Special Issue. Within the articles, CMOS gas sensors are assessed for gas mixture analysis; CMOS-MEMS pixel sensors are used for thermal neutron imaging; resistive microbolometers are fabricated via the CMOS process; an MEMS Pirani sensor is utilized for in situ pressure distribution sensing; CMOS low-noise amplifiers, power amplifiers, and energy micro-harvesters are manufactured using CMOS-MEMS technology; and high aspect ratio TSVs are used for 3D integration. This Reprint is especially relevant for any readers with an interest in the abovementioned topics.

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